

PX 100

compact 1-axis translation stage

Concept:

The systems of the series PX 100 are ideally suited for nm-precise positioning of optic components such as mirrors and laser diodes, adjustment and mounting in semiconductor technologies and electronics, and applications in measurement technologies and quality assurance as well as microbiology.

The series PX consist of piezo electrical actuator in stage design with a solid top and bottom plate for easily integration in optical setups. The monolithic flexure hinges design offers high precision motion range, high stiffness and in due of this excellent dynamical performance for extremely fast and accurate positioning tasks

Specials:

The systems of this series are available in vacuum and cryogenic temperature configurations. As an option they may come equipped with strain gage or capacitive position sensors, depending on the system configuration, to achieve very accurate repeatability in the low nanometer range.

Interfaces:

The elements of the series PX are actuators integrated with an inner lever transmission in housing. Since the lever mechanism works in both directions, pulling forces between bottom and top plate need to be avoided, as they could damage the stage. The stage is fixed to a base plate.

Components can be mounted on the top plate by two threaded diagonal holes and can be accurately affixed using the precise pin holes.



image: PX 100

Product highlights:

- accurate parallel motion
- up to 100µm motion range
- without mechanical play
- easily combined with other piezo electrical systems
- precison pin holes for accurate adjustment
- high dynamic range

Applications:

- fiber positioning
- beam alignment
- semiconductor
- micro manipulation





PX 100

Technical data:

part no. T-104-00 T-10 axis - X motion in open(±10%)/closed loop (±0.2%)* μm 100/ - 100 capacitance (±20%)** μF 1.8 1 resolution (open/closed loop)*** nm 0.2/ - 0. integrated measurement system - - - strain typ. repeatability nm - ±	00 SG 04-01 X 0/80 L.8 2/2 gage	
axis - X motion in open(±10%)/closed loop (±0.2%)* μm 100/ - 100 capacitance (±20%)** μF 1.8 1 resolution (open/closed loop)*** nm 0.2/ - 0. integrated measurement system - - - strain typ. repeatability nm - ±	X 0/80 1.8 2/2	
motion in open($\pm 10\%$)/closed loop ($\pm 0.2\%$)* µm 100/ - 100 capacitance ($\pm 20\%$)** µF 1.8 1.8 resolution (open/closed loop)*** nm 0.2/ - 0.0 integrated measurement system strain typ. repeatability nm - \pm	0/80 L.8 2/2	
capacitance (±20%)**	L.8 2/2	
resolution (open/closed loop)*** nm 0.2/- 0. integrated measurement system strain typ. repeatability nm - ±	2/2	
integrated measurement system strain typ. repeatability nm - ±	•	
typ. repeatability nm - ±	gage	
typ. non-linearity % - 0	4	
	.02	
resonant frequency (unloaded) Hz 790 7	'90	
max. push/pull forces N 150/15 15	0/15	
stiffness N/μm 0.35 0	.35	
voltage range V -20130V -20	130V	
- LEMO 0S 302	302/ LEMO .304	
cable length m 1	1.2	
temperature range °C -20°C +80°C -20°C +80°C	+80°C	
material - aluminum/stainless stee	aluminum/stainless steel	
dimensions (LxWxH) mm 40x40x20 40x4	40x20	

^{*} typical value measured with NV 40/3 amplifier (closed loop: NV 40/3 CLE amplifier)

**** additional connector configurations

	an connector configurations		
Product name	Description	Specials	Part. No Suffix.
PX 100 SG Digital	Version for digital controller series d-Drive and 30DV50 in combination with additional functionalities: Interchangeability, ASI, ASC	Connector Sub-D 15	T-104-01D
PX 100 SG Extern	Version with sensor pre-amplifier for the use with "CLE" amplifier units and with the additional functionalities: Interchangeability, ASI	Connector Sensor: ODU 4pin	T-104-01E

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^{**} typical value for small electrical field strength

^{***} the resolution is only limited by the noise of the power amplifier and metrology